

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Application Number

10/645020

Filing Date

August 21, 2003

First Named Inventor

Lu, David D.

Art Unit

~~1762~~ 1756

Examiner Name

Barreca

Attorney Case Number

58934US002

U.S. Patent Documents

Exam. Init.*	Cite No.	Document Number	Publication Date or Issue Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Doc. Number-(Kind Code if Known)			
	A1	US-			
	A2	US-			
	A3	US-			
	A4	US-			
	A5	US-			
	A6	US-			
	A7	US-			
	A8	US-			
	A9	US-			
	A10	US-			

Foreign Patent Documents

Exam. Init.*	Cite No.	Foreign Patent Document		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	Translation (Check if yes)
		Ctry. Code	Number-KindCode (if known)				
ny	B1	JP	04073652	03-09-1992	English abstract		
ny	B2	JP	05313376	11-26-1993	English abstract		
ny	B3	JP	11080594	03-26-1999	English abstract		
ny	B4	JP	62-42160	02-24-1987	English abstract		

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS

Exam. Init.*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published
ny	C1	DAVID P. MANCINI et al., "Low surface energy polymeric release coating for improved contact print lithography", 21 st Annual BACUS Symposium on Photomask Technology, Giang T. Dao, Brian J. Grenon, Editors, Proceedings of SPIE Vol. 4562 (2002), pp. 593-599
ny	C2	International Search Report for PCT/US2004/021017
	C3	
	C4	

*Examiner:

Nick Barreca

Date Considered:

11/10

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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ms	A1	US- 3,306,855	02-28-1967	Borecki	508/1431
	A2	US- 3,492,374	01-27-1970	LeBleu et al.	558/186
	A3	US- 5,032,279	07-16-1991	Lee	210/1640
	A4	US- 5,132,446	07-21-1992	Tohzuka et al.	558/186
	A5	US- 5,256,318	10-26-1993	Masutani et al.	252/1757
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	A7	US- 5,851,674	12-22-1998	Pellerite et al.	423/421
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	B1						
	B2						

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ms	C1	JOHN G. VAN ALSTEN, "Self-Assembled Monolayers on Engineering Metals: Structure, Derivatization, and Utility", Langmuir 1999, 15, 7605-7614
ms	C2	F. SINAPI, L. FORGET, J. DELHALLE and Z. MEKHALIF, "Formation and characterization of thin films of $H(CH_2)_xPO(OH)_2$ on polycrystalline zinc substrates", Surf. Interface Anal. 2002; 34: 148-154
	C3	
	C4	

*Examiner:

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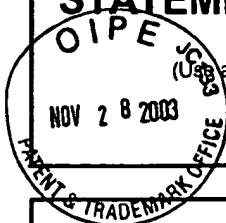
Information Disclosure Statement)

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ny	A1	US- 3,810,874	05/1974	Mitsch, et al.	527/170
	A2	US- 4,514,489	04/1985	Garcia et al.	430/327
	A3	US- 4,735,890	04/1988	Nakane	430/311
	A4	US- 5,286,567	02/1994	Kubota et al.	427/422
	A5	US- 5,356,736	10/1994	Kita et al.	429/337
	A6	US- 5,602,225	02/1997	Montagna et al.	527/25
	A7	US- 6,277,485 B1	08/2001	Invie et al.	427/336
	A8	US- 6,300,042 B1	10/2001	Mancini et al.	430/325
✓	A9	US- 6,387,787 B1	05/2002	Mancini et al.	437/586
ny	A10	US- App. 10/161,258	05/2002	Boardman, et al.	427/457

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ny	B1	EP	0 603 697 B1	03.09.1997	Strepparola, et al.		
	B2						

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ny	C1	C. Tonelli, et al., "Linear perfluoropolyether difunctional oligomers: chemistry, properties and applications", Journal of Fluorine Chemistry 95, 1999, pp. 51-70.
	C2	C. T. Yim et al., "Dynamics of Octadecylphosphonate Monolayers Self-Assembled on Zirconium Oxide: A Deuterium NMR Study", J. Phys. Chem, B 2002, 106, 1728-1733
✓	C3	D. L. Flowers, "Lubrication in Photolithography", J. Electrochem. Soc.: Solid-State Science and Technology, Vol. 124, October 1977, pp. 1608-1612
ny	C4	Toshiharu Matsuzawa et al., "Surface Conversion for Antisticking to Reduce Patterning Defects in Photolithography", J. Electrochem. Soc.: Solid-State Science and Technology, Vol. 128, No. 1, January 1981, pp. 184-187.

*Examiner:

Wickham

Date Considered:

1/6/04

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